

Lecture 3

Basic Sensors: Displacement, Strain, and Pressure

References

Webster, Ch. 2 (Sec. 2.1-2.4).

<http://en.wikipedia.org/wiki/Potentiometer>

http://en.wikipedia.org/wiki/Strain_gauge

http://en.wikipedia.org/wiki/Wheatstone_bridge

BASIC SENSORS

Webster, Chap. 2

A sensor is a type of transducer : it converts a physical parameter into an electrical signal.

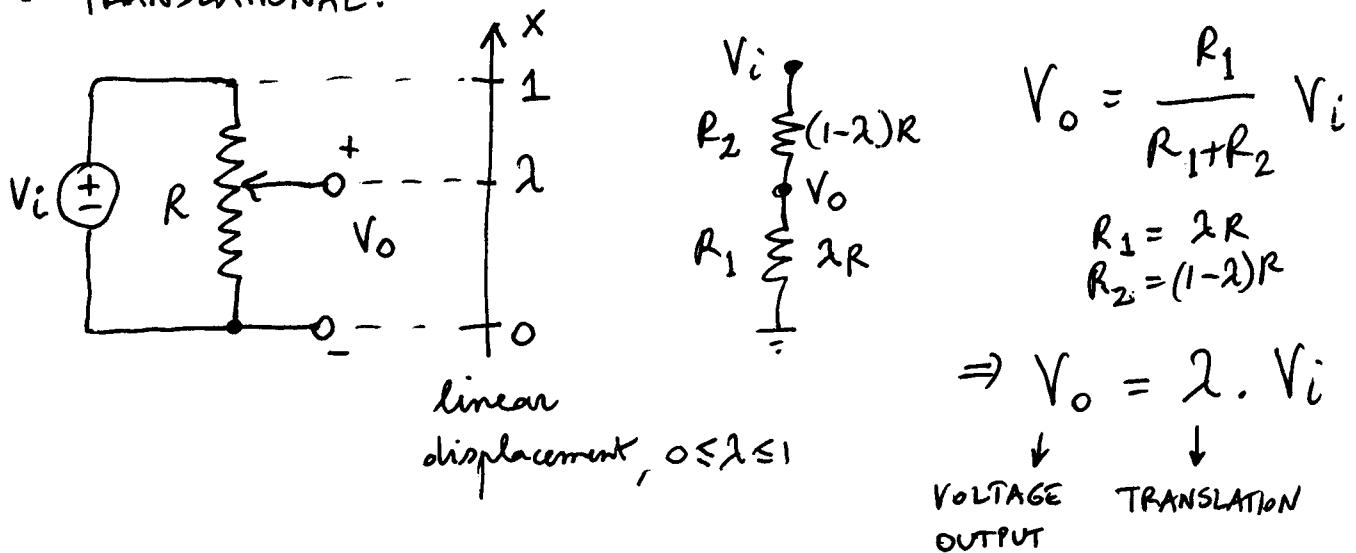
Here we will just consider :

- Physical parameters:
 - DISPLACEMENT : main parameter used to measure STRAIN, ACCELERATION, FORCE, STRESS, PRESSURE, etc.
 - TEMPERATURE
- Electrical signals:
 - VOLTAGE or CHARGE, directly transduced
 - IMPEDANCE :
 - R : resistive sensor
 - L : inductive sensor
 - C : capacitive sensorindirectly transduced to VOLTAGE through
 - ~ VOLTAGE DIVIDER or a WHEATSTONE BRIDGE.

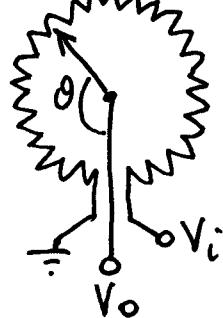
- Resistive displacement sensors

- Potentiometer : a voltage divider which transduces position into voltage through a ratio of resistances:

- TRANSLATIONAL:



- SINGLE TURN:



angular displacement,
 $\theta_{\min} \leq \theta \leq \theta_{\max}$

$$V_o = \frac{R_1}{R_1 + R_2} V_i$$

$$R_1 = 2\lambda R$$

$$R_2 = (1-\lambda)R$$

$$\text{where } \lambda = \frac{\theta - \theta_{\min}}{\theta_{\max} - \theta_{\min}}$$

$$\Rightarrow V_o = \frac{\theta - \theta_{\min}}{\theta_{\max} - \theta_{\min}} \cdot V_i$$

↓ ↓
VOLTAGE RELATIVE
OUTPUT TURN

typically θ_{\min} : close to 0

θ_{\max} : close to 2π (360°)

- MULTITURN : N windings \Rightarrow

θ_{\min} : close to 0

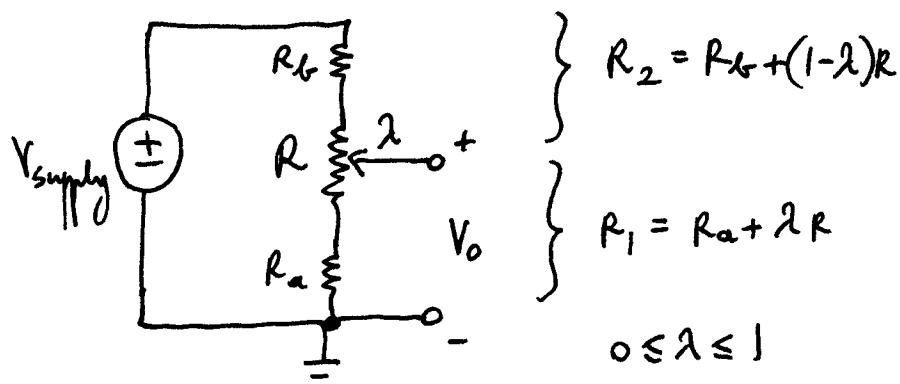
θ_{\max} : close to $2\pi N$ ($360^\circ \times N$)

NOTE :

Typically, V_i is a supply voltage V_{supply} , such as a battery. The output V_o then ranges between GND (0V) and V_{supply} .

Problem: some signal processing circuits can't handle inputs close to the power supply rails (GND and V_{supply}), so that small and large displacements λ (turns) may be cut off.

Solution: add series resistors between the supplies and the potentiometer:

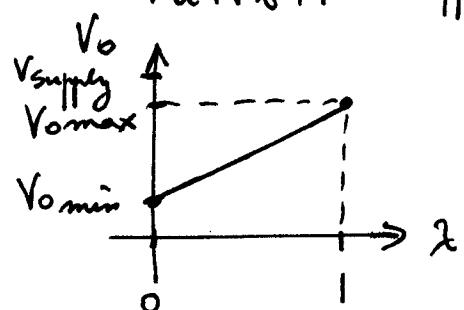


$$\left. \begin{array}{l} R_2 = R_b + (1-\lambda)R \\ R_1 = R_a + \lambda R \end{array} \right\} 0 \leq \lambda \leq 1$$

$$V_o = \frac{R_1}{R_1 + R_2} \cdot V_{\text{supply}}$$

$$\Downarrow$$

$$V_o = \frac{R_a + \lambda R}{R_a + R_b + R} \cdot V_{\text{supply}}$$



Example : $V_{\text{supply}} = 5V$
 $R = 10k\Omega$

Choose R_a and R_b such that the output range is $1V \leq V_o \leq 4V$ (1V of margin on both sides).

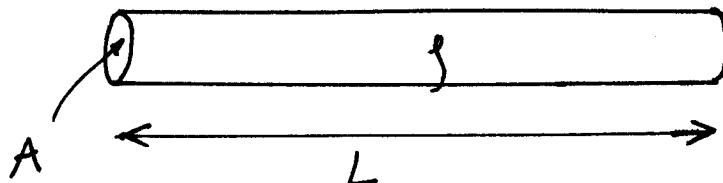
$$\rightarrow R_a = R_b = \frac{R}{3} = 3.33k\Omega$$

$$V_{\text{min}} : \frac{R_a}{R_a + R_b + R} \cdot V_{\text{supply}}$$

$$V_{\text{max}} : \frac{R_a + R}{R_a + R_b + R} \cdot V_{\text{supply}}$$

— Strain gauge (or "gage") : more sensitive for very small displacements

Wire resistance depends on geometry that changes with STRAIN



g : resistivity [Ω·m]

resistance : $R = g \cdot \frac{L}{A}$ depends on MATERIAL (g)
GEOMETRY (L, A)

A very small change in length $L \rightarrow L + dL$ results in a change in resistivity $g \rightarrow g + dg$ and area $A \rightarrow A + dA$, which combine into a change in resistance $R \rightarrow R + dR$:

$$dR = \frac{g}{A} dL - \frac{gL}{A^2} dA + \frac{L}{A} dg, \text{ or:}$$

$$\frac{dR}{R} = \frac{dL}{L} - \frac{dA}{A} + \frac{dg}{g}$$

Poisson's ratio relates change in diameter to change in length:

$$\frac{dD}{D} = -\mu \cdot \frac{dL}{L} \quad \text{where } A = \frac{\pi D^2}{4}, \text{ or } \frac{dA}{A} = 2 \frac{dD}{D}$$

\downarrow
POISSON'S
RATIO
(≈ 0.3
for metals)

$$\Rightarrow \frac{dA}{A} = -2\mu \cdot \frac{dL}{L}$$

$$\Rightarrow \frac{dR}{R} = \underbrace{(1 + 2\mu)}_{\text{DIMENSIONAL EFFECT}} \cdot \frac{dL}{L} + \underbrace{\frac{dg}{g}}_{\text{PIEZORESISTIVE EFFECT}}$$

Gauge factor ("gage" factor) G : ratio of (small) relative changes in resistance and length:

$$G \stackrel{\text{def.}}{=} \frac{\Delta R/R}{\Delta L/L} = 1 + 2\mu + \frac{\Delta g/g}{\Delta L/L} \quad (\Delta L/L \ll 1)$$

depends on the material:

- metals: $\Delta g/g \approx 0$ and $\mu \approx 0.5 \Rightarrow G \approx 2$

- semiconductors: $\Delta g/g / \Delta L/L \approx \pm 100 \Rightarrow G \approx \pm 100$, but temperature sensitive \Rightarrow requires temperature compensation such as in a bridge.

NOTE: Several measurands fit the displacement category:

- STRAIN: $\varepsilon \stackrel{\text{def.}}{=} \frac{\Delta L}{L} \Rightarrow \frac{\Delta R}{R} = G \cdot \varepsilon$

- STRESS: $\sigma \stackrel{\text{def.}}{=} \frac{F}{A}$ force per unit area

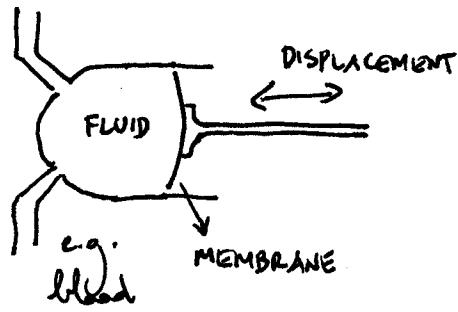
Young's Modulus: $E = \frac{\sigma}{\varepsilon} = \frac{F/A}{\Delta L/L}$ depends on the material

$$\Rightarrow \frac{\Delta R}{R} = G \cdot \varepsilon = \frac{G}{E} \cdot \sigma$$

- PRESSURE: like stress, but for fluids etc...

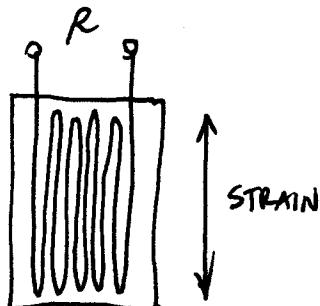
Physical strain gauge:

- unbonded, e.g.: pressure sensor



Fluid pressure
→ membrane displacement
→ wire elongation
→ resistance change

- bonded



wire on film/jail substrate
which is conformal to host
surface and hence directly
measures its strain.

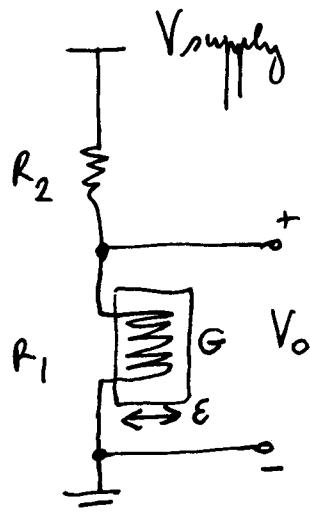
N turns

→ N times greater resistance R
→ N times greater sensitivity
 $\Delta R / \epsilon$

- typically embedded in a voltage divider, or a differential voltage divider (Wheatstone bridge), ideally with temperature compensation.

It is best to match resistance values and their temperature coefficients, at least in pairs.

Example: Voltage divider structure with single strain gauge :



$$V_o = \frac{R_1}{R_1 + R_2} \cdot V_{\text{supply}}$$

$$\begin{aligned} dV_o &= \left(\frac{dR_1}{R_1 + R_2} - \frac{R_1}{(R_1 + R_2)^2} \cdot dR_1 \right) V_{\text{supply}} \\ &= \frac{R_2 \cdot dR_1}{(R_1 + R_2)^2} \cdot V_{\text{supply}} \end{aligned}$$

$$\text{where } dR_1 = G \cdot E \cdot R_1$$

$$\Rightarrow dV_o = \frac{R_1 R_2}{(R_1 + R_2)^2} \cdot G \cdot E \cdot V_{\text{supply}}$$

$$\Rightarrow \text{Sensitivity: } \frac{dV_o}{E} = \frac{R_1 R_2}{(R_1 + R_2)^2} \cdot G \cdot V_{\text{supply}}$$

- Find R_2 to maximize sensitivity

$$\Rightarrow R_2 = R_1 \Rightarrow \frac{R_1 R_2}{(R_1 + R_2)^2} = \frac{1}{4}$$

- What is the temperature coefficient if R_1 and R_2 have identical temperature coefficients?

$$\begin{aligned} R_1 &\rightarrow (1 + \alpha \Delta T) R_1 \\ R_2 &\rightarrow (1 + \alpha \Delta T) R_2 \end{aligned} \Rightarrow \frac{R_1 R_2}{(R_1 + R_2)^2} \rightarrow \frac{(1 + \alpha \Delta T)^2}{(1 + \alpha \Delta T)^2} \cdot \frac{R_1 R_2}{(R_1 + R_2)^2}$$

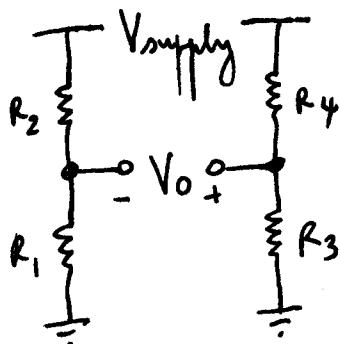
\Rightarrow zero temperature coefficient in the sensitivity

\rightarrow TEMPERATURE COMPENSATED SENSITIVITY

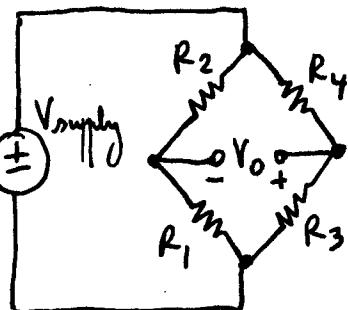
WHEATSTONE BRIDGE (or "bridge" for short):

Differential combination of two voltage dividers

- linear
- zero offset
- high sensitivity
- temp. compensated



or:



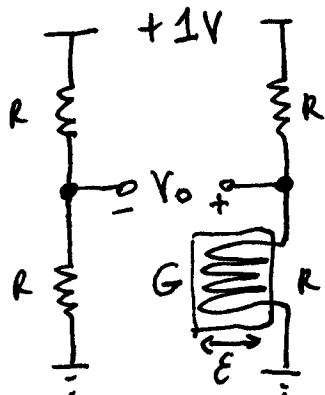
$$V_o = \left(\frac{R_3}{R_3+R_4} - \frac{R_1}{R_1+R_2} \right) V_{\text{supply}}$$

$$\text{or } V_o = 0 \text{ for } \frac{R_1}{R_2} = \frac{R_3}{R_4} \text{ (balanced)}$$

Ideally $R_1 = R_2 = R_3 = R_4$ for maximum sensitivity.

Any of R_1, R_2, R_3, R_4 or their combinations can be strain gauges, ideally differentially matched in pairs.

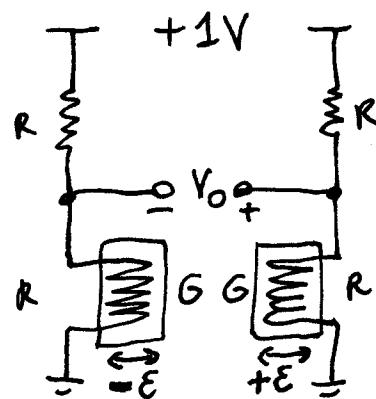
Examples:



\Rightarrow SENSITIVITY:

$$\frac{V_o}{E} = \frac{1}{4} G \cdot 1V$$

\rightarrow LOWEST
not T comp.

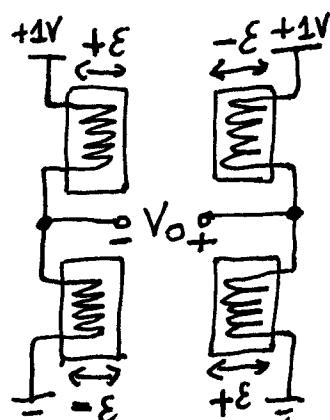


differentially activated
(one pulls, the other pushes)

\Rightarrow SENSITIVITY:

$$\frac{V_o}{E} = \frac{1}{2} G \cdot 1V$$

T comp.



double differentially activated

\Rightarrow SENSITIVITY:

$$\frac{V_o}{E} = G \cdot 1V$$

\rightarrow HIGHEST
T comp.

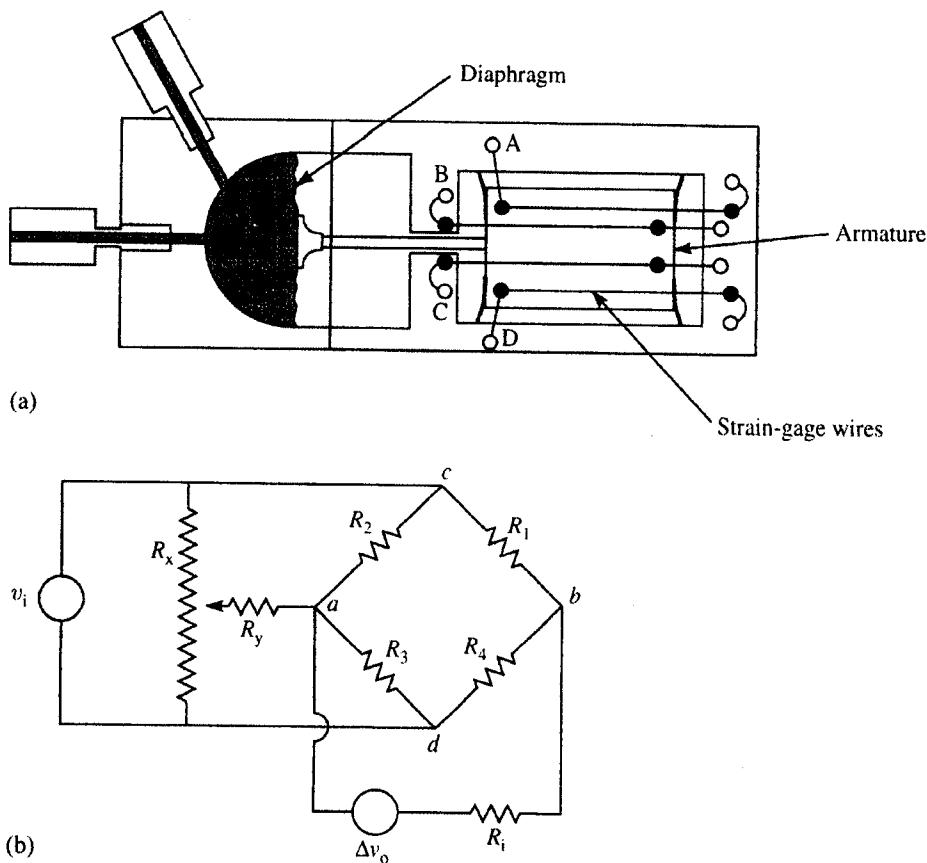


Figure 2.2 (a) Unbonded strain-gage pressure sensor. The diaphragm is directly coupled by an armature to an unbonded strain-gage system. With increasing pressure, the strain on gage pair B and C is increased, while that on gage pair A and D is decreased. (b) Wheatstone bridge with four active elements: $R_1 = B$, $R_2 = A$, $R_3 = D$, and $R_4 = C$ when the unbonded strain gage is connected for translational motion. Resistor R_y and potentiometer R_x are used to initially balance the bridge, v_i is the applied voltage, and Δv_o is the output voltage on a voltmeter or similar device with an internal resistance of R_i .